

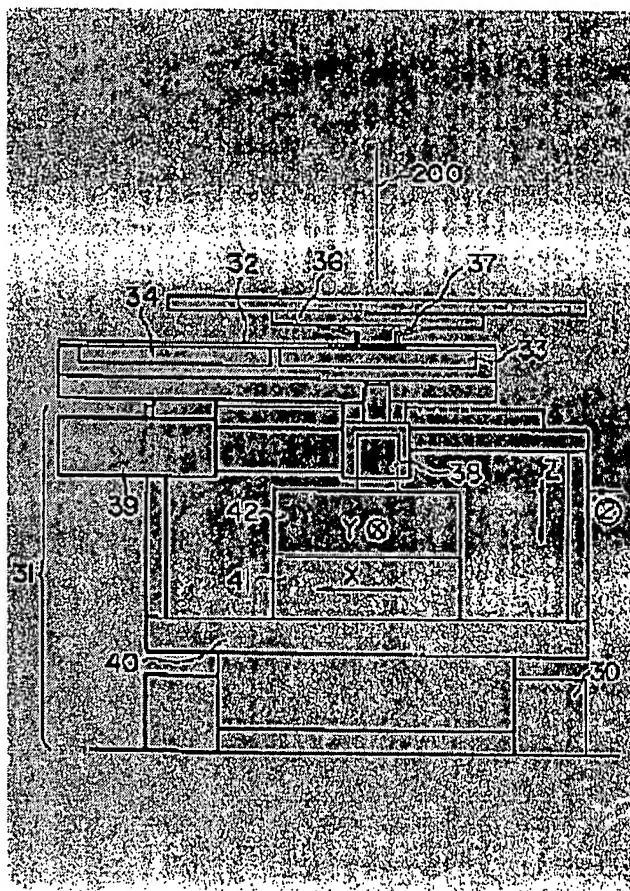
PROBE CARD INSPECTION METHOD

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Abstract of JP7005078

PURPOSE: To rapidly and accurately judge whether a needle tip is located properly or not by pressing a glass flat plate to a measurement needle, tracing a plurality of needle tips successively from the glass flat plate side according to card data, and then displaying a needle tip image along with a judging reference frame. **CONSTITUTION:** The height and contact resistance of a needle tip can be measured by moving a compound inspection substrate 32 up and down in Z direction by a elevating and lowering unit 31 and then moving an electrode flat plate 33 while pressing it to a measurement needle 37 of a probe card 36. On the other hand, the needle tip positions of a plurality of measurement needles 37 can be inspected automatically by measuring the needle tip positions of the plurality of measurement needles 37 while moving an optical microscope 38 and a CCD camera 39 to a desired plane coordinate position with XY tables 41 and 42 and then displaying them along with the measurement reference frame on a display while a transparent glass flat plate 34 is being pressed to the measurement needles 37 by a specific amount.



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